

Docket No.: 50090-334

PATENT**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of :

Masanobu IWASAKI, et al. :

Serial No.: 09/934,474 :

Group Art Unit: 3723

Filed: August 23, 2001 :

Examiner: H. Shakeri

For: POLISHING SOLUTION SUPPLY SYSTEM, METHOD OF SUPPLYING POLISHING
SOLUTION, APPARATUS FOR AND METHOD OF POLISHING SEMICONDUCTOR
SUBSTRATE AND METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
Washington, DC 20231

Sir:

It is respectfully requested that the time for response to the Office Action dated April 18, 2002, now due to expire July 18, 2002, be extended for two months and set to expire on September 18, 2002.

Please charge the extension fee of \$400.00 to Deposit Account No. 500417. Please charge any additional fees or credit any overpayment to Deposit Account No. 500417.

Respectfully submitted,

MCDERMOTT, WILL & EMERY

Arthur J. Steiner

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